What is claimed is:

1. A degassing chamber, comprising a chamber and a substrate cassette, the chamber having a substrate transferring opening on its sidewall, the substrate transferring opening serving as a path through which one or more substrates are transferred into or out of the chamber; and the substrate cassette being movable along a vertical direction in the chamber, wherein the degassing chamber further comprises a heating assembly disposed in the chamber, the heating assembly comprises a first light source and a second light source, the chamber is divided into a first chamber and a second chamber by the substrate transferring opening as a boundary; the first light source is in the first chamber, the second light source is in the second chamber; and the first light source and the second light source are configured to heat the substrates in the substrate cassette; and

the heating assembly further comprises a first reflecting cylinder and a second reflecting cylinder, the first reflecting cylinder is between the first chamber and the first light source; the second reflecting cylinder is between the second chamber and the second light source; and

the first reflecting cylinder and the second reflecting cylinder are configured to reflect light illuminated thereon toward the substrates in the substrate cassette; and

the first reflecting cylinder and the second reflecting cylinder abut each other to form an integral whole, on which a first opening is provided at a position corresponding to the substrate transferring opening, and the first opening allows substrates to pass therethrough.

2. The degassing chamber according to claim 1, wherein the first light source is disposed at an inner side of a sidewall of the first chamber in such a way that it surrounds the first chamber along a circumferential direction of the first chamber; the second light source is disposed at an inner side of a sidewall of the second chamber in such a way that it surrounds the second chamber along a circumferential direction of the second chamber; and

the substrate cassette is movable in a space surrounded by the first light source and the second light source.

3. The degassing chamber according to claim 2, wherein the first light source comprises a plurality of first line light sources, a length of each of the first line light sources lies in a direction parallel to a moving direction of the substrate cassette; and the plurality of first line light sources are parallel to each other and arranged circularly along a circumferential direction of the chamber; and

the second light source comprises a plurality of second line light sources, a length of each of the second line light sources lies in the direction parallel to the moving direction of the substrate cassette; and the plurality of second line light sources are parallel to each other and arranged circularly along the circumferential direction of the chamber.

4. The degassing chamber according to claim 3, wherein any adjacent two of the plurality of first line light sources are spaced apart by a same distance; any adjacent two of the plurality of second line light sources are spaced apart by a same distance.

5. The degassing chamber according to claim 1, wherein the heating assembly further comprises a first reflecting plate and a second reflecting plate, the first reflecting plate covers an end of the first reflecting cylinder distal to the substrate transferring opening, and the second reflecting plate covers an end of the second reflecting cylinder distal to the substrate transferring opening; and

the first reflecting plate and the second reflecting plate are configured to reflect light illuminated thereon toward the substrate cassette.

6. The degassing chamber according to claim 1, wherein inner walls of the first reflecting cylinder and the second reflecting cylinder are capable of reflecting diffusely and/or specularly light illuminated thereon.

7. The degassing chamber according to claim 5, wherein an inner wall of the first reflecting plate facing inside of the first reflecting cylinder and an inner wall of the second reflecting plate facing inside of the second reflecting cylinder are capable of reflecting diffusely and/or specularly light illuminated thereon.

8. The degassing chamber according to claim 1, wherein the first reflecting cylinder and the second reflecting cylinder are made of stainless steel.

9. The degassing chamber according to claim 5, wherein the first reflecting plate and the second reflecting plate are made of stainless steel.

10. A semiconductor processing device, comprising the degassing chamber according to any one of claims 1 to 9.